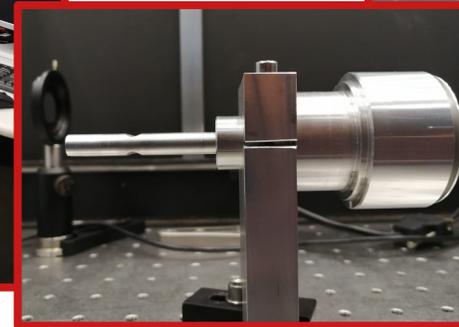
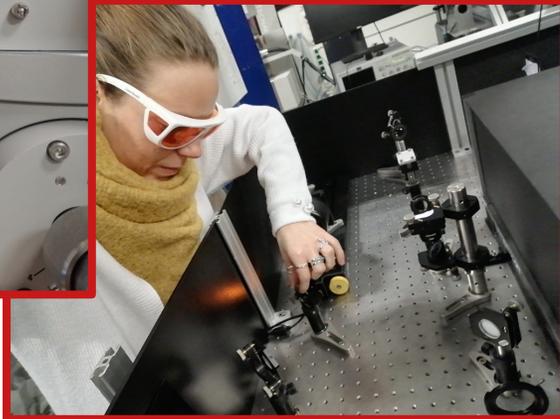
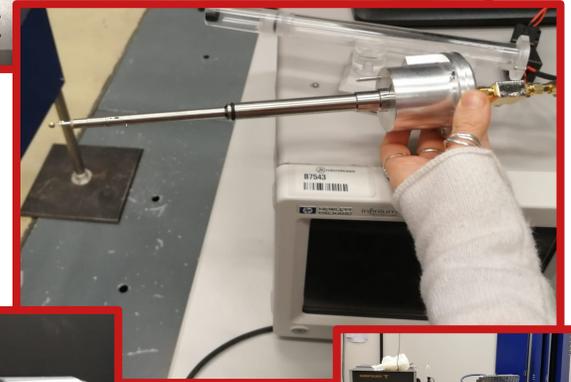
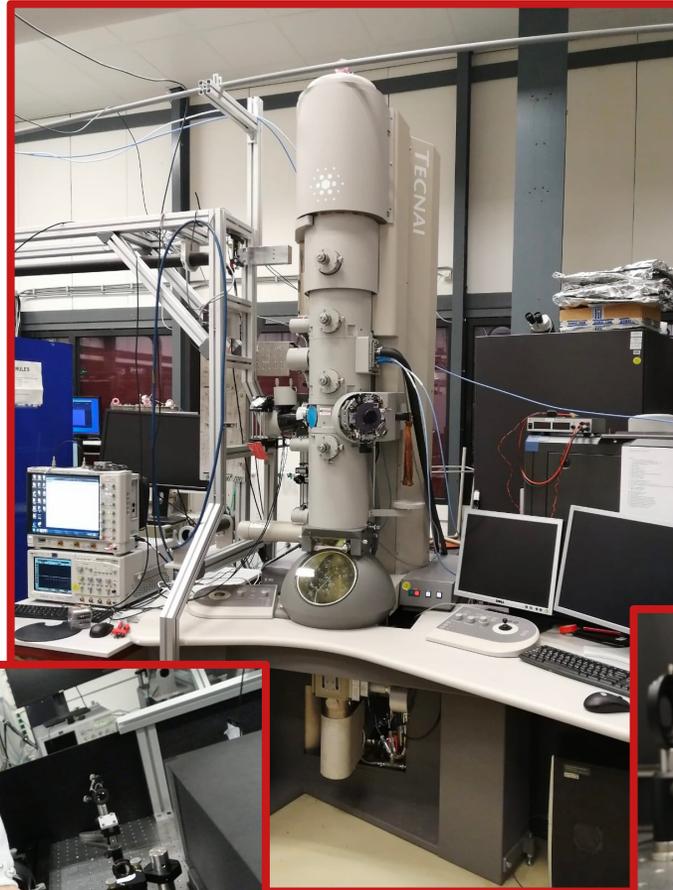
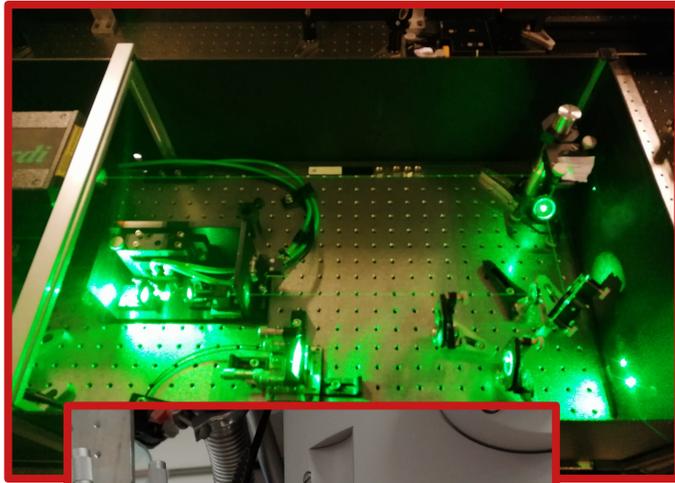


The background of the slide is a composite image. The left side shows a grayscale, textured surface, possibly a material or a biological structure. The right side shows a vibrant, golden-yellow surface with numerous small, circular, bubble-like structures, resembling a porous material or a biological cell structure. A jagged, torn-paper-like border separates the two images.

Free-electrons manipulation with light in an RF-cavity-based Ultrafast Transmission Electron Microscope

Simona Borrelli

Ultrafast Transmission Electron Microscopy Technology



Growth of carbon nanofibre

06:05.000

200 nm

E. Miniach et al., 2016

Supporting_Video_S1 X. Dai et al., 2021
TEM tilt series of double spiral lamellar morphology

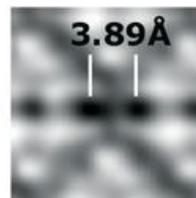
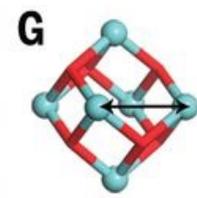
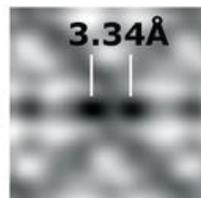
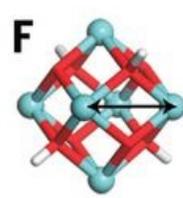
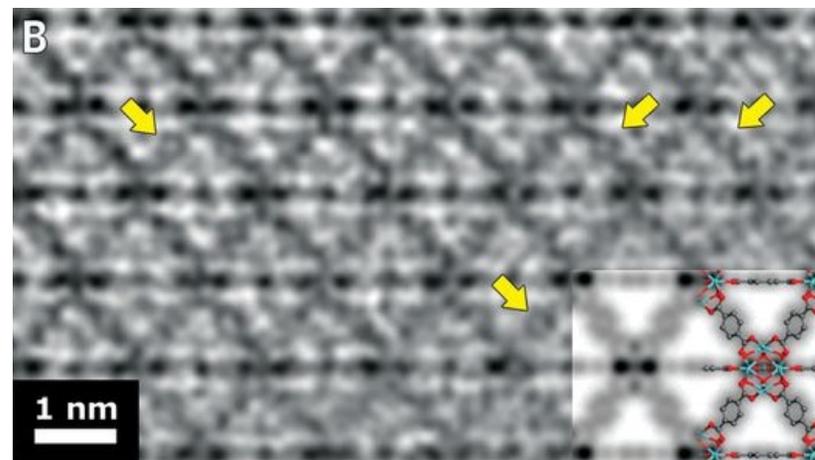
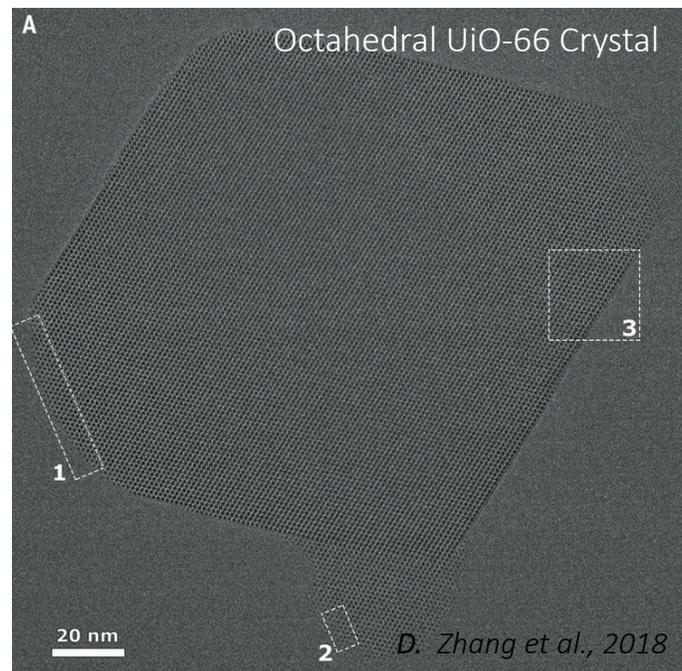
Tilt angle $-60.8^\circ \sim +47.6^\circ$

100 nm

Star-shaped gold nanoparticle

20 nm

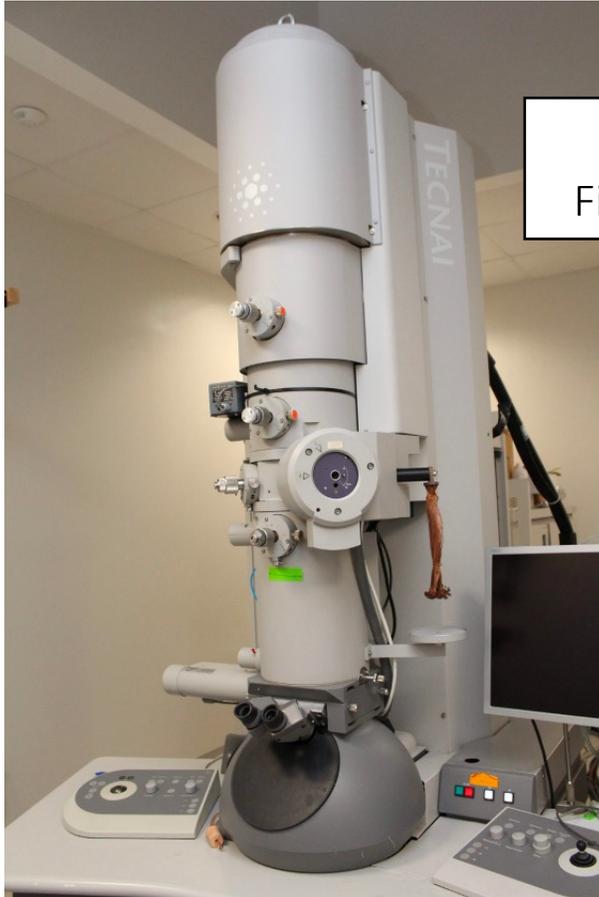
C. L. Nehl et al., 2006



Ultrafast Transmission Electron Microscopy

Ultrafast Transmission Electron Microscope

Continuous electron beam



Schottky
Field Emission Gun

Brightness

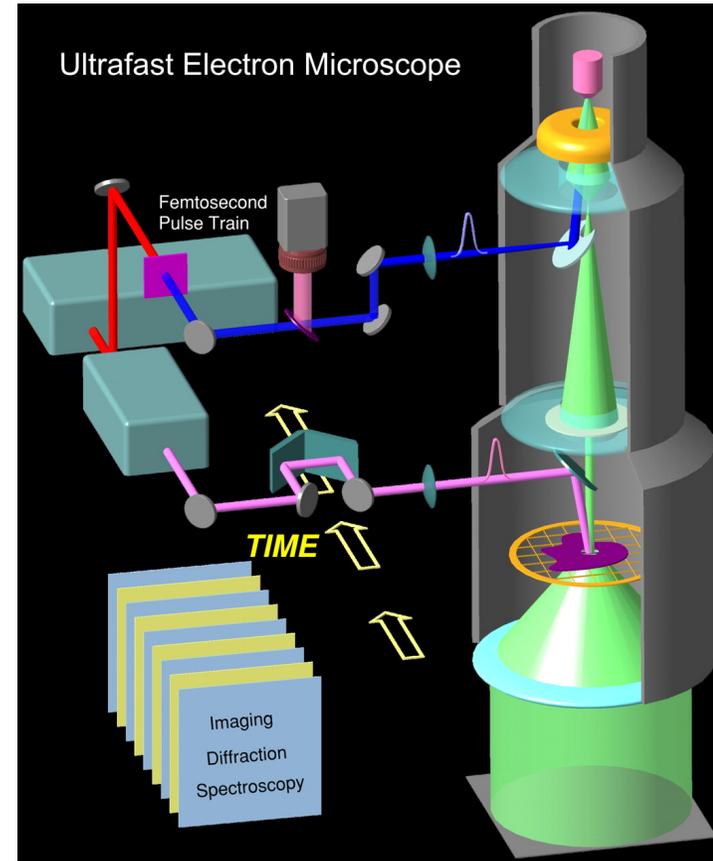
$$B_r = \frac{q_e}{m_e c^2} \frac{I}{4 \pi^2 \epsilon_{n,x} \epsilon_{n,y}} \sim 10^7 (\text{A} / \text{m}^2 \text{sr V})$$

Beam coherence approaching the
limit imposed by Heisenberg's
uncertainty principle

Atomic spatial resolution

Ultrafast Transmission Electron Microscope

Continuous electron beam

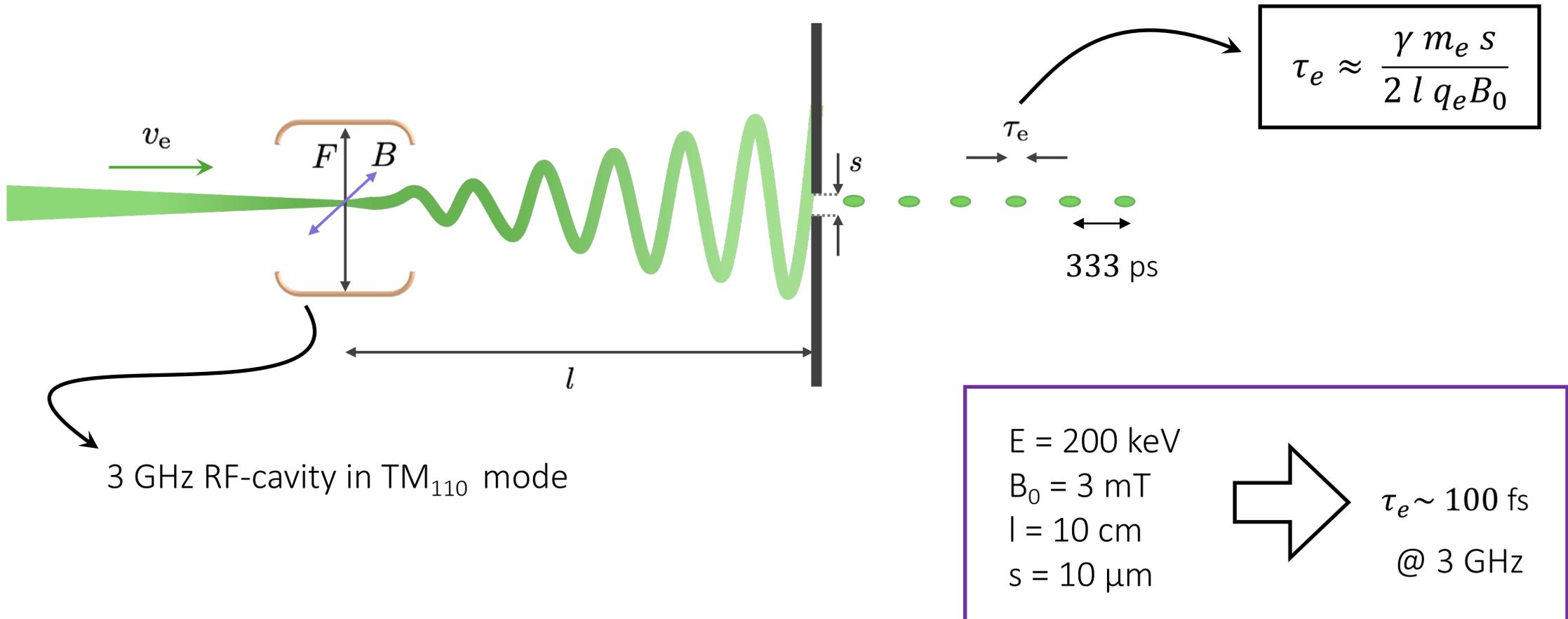


Photoemitted pulsed
electron beam

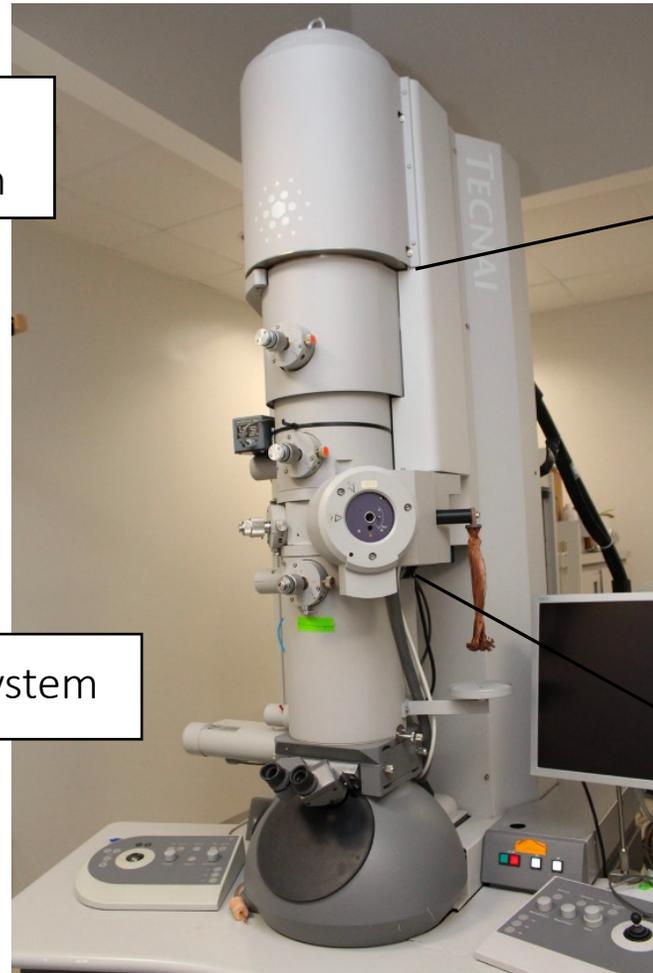
Lobastov et al., Proc. National Academy of Science, 2005, 7069-7073

Atomic spatial and temporal resolution

Pulse Generation by Beam Chopping



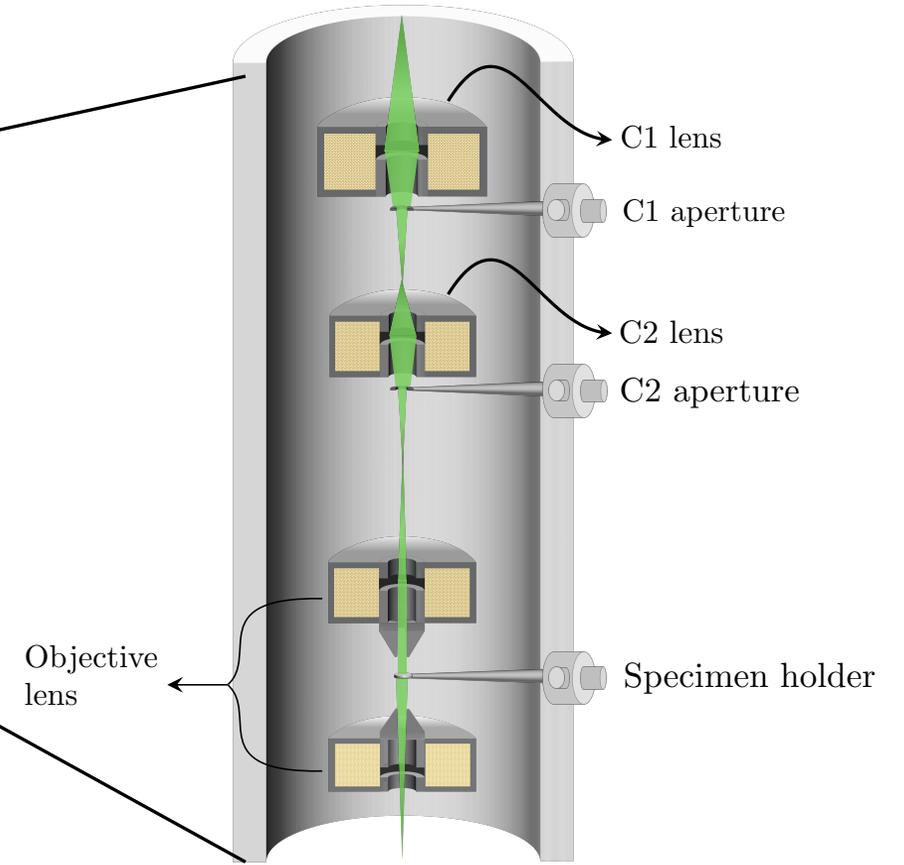
RF-Cavity-Based Ultrafast Transmission Electron Microscope



Schottky
Field Emission Gun

200 keV Tecnai TF20
Continuous electron beam

Projection System

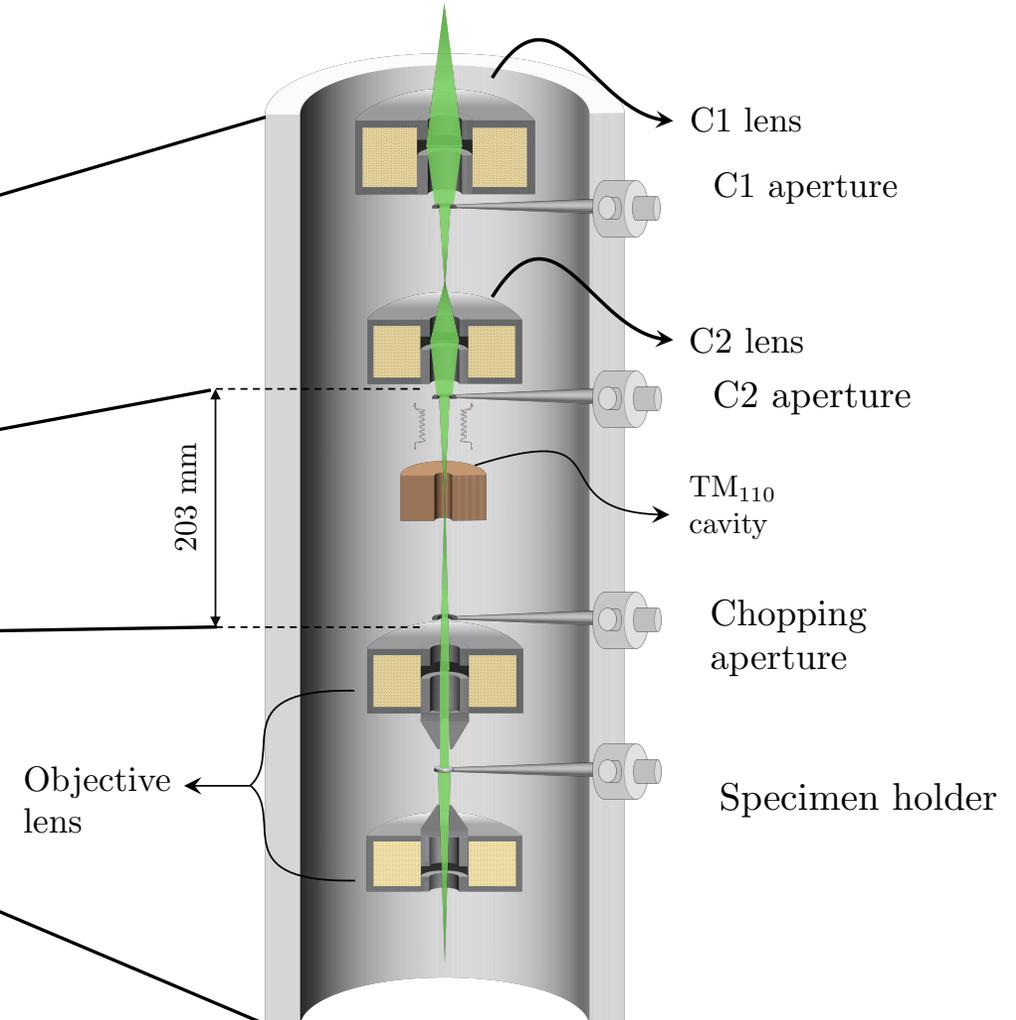
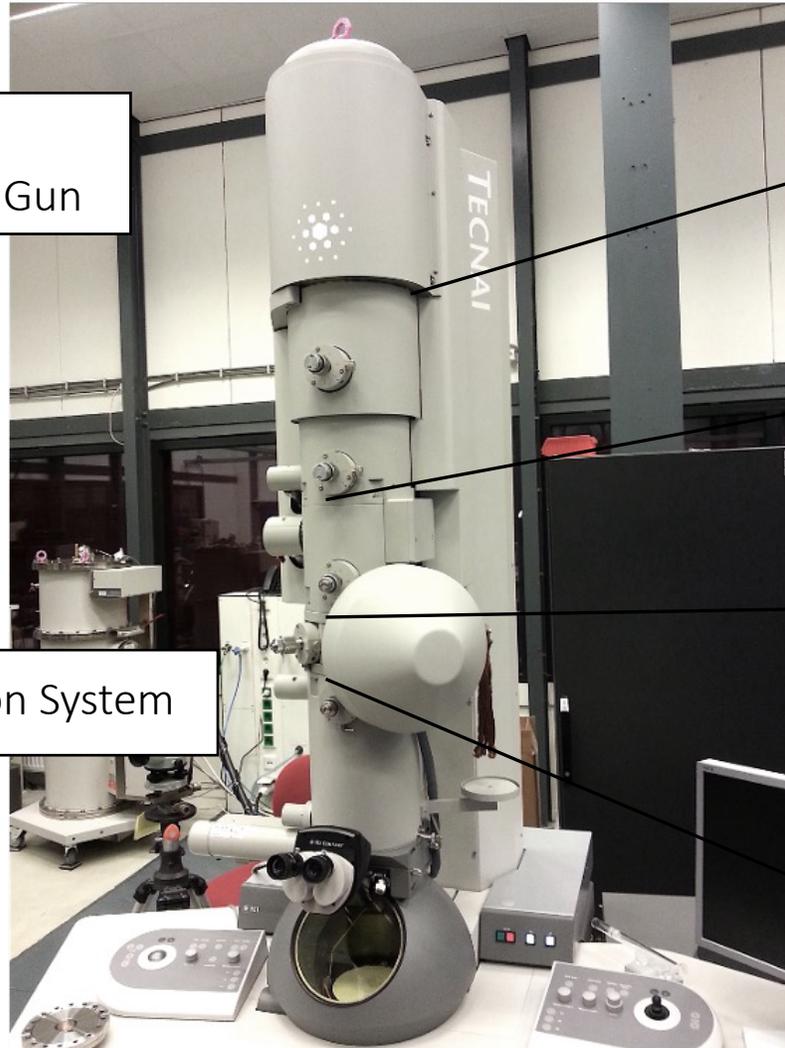


RF-Cavity-Based **U**ltrafast **T**ransmission **E**lectron **M**icroscope

Schottky
Field Emission Gun

200 keV Tecnai TF20
Pulsed electron beam

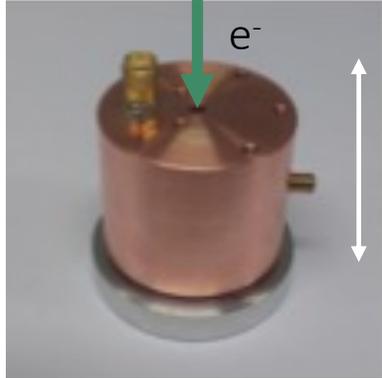
Projection System



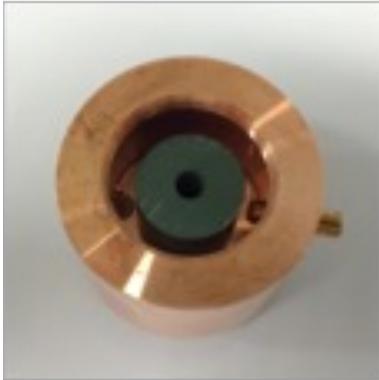
TM₁₁₀ RF-Cavity in UTEM



Miniaturized TM₁₁₀ RF-cavity

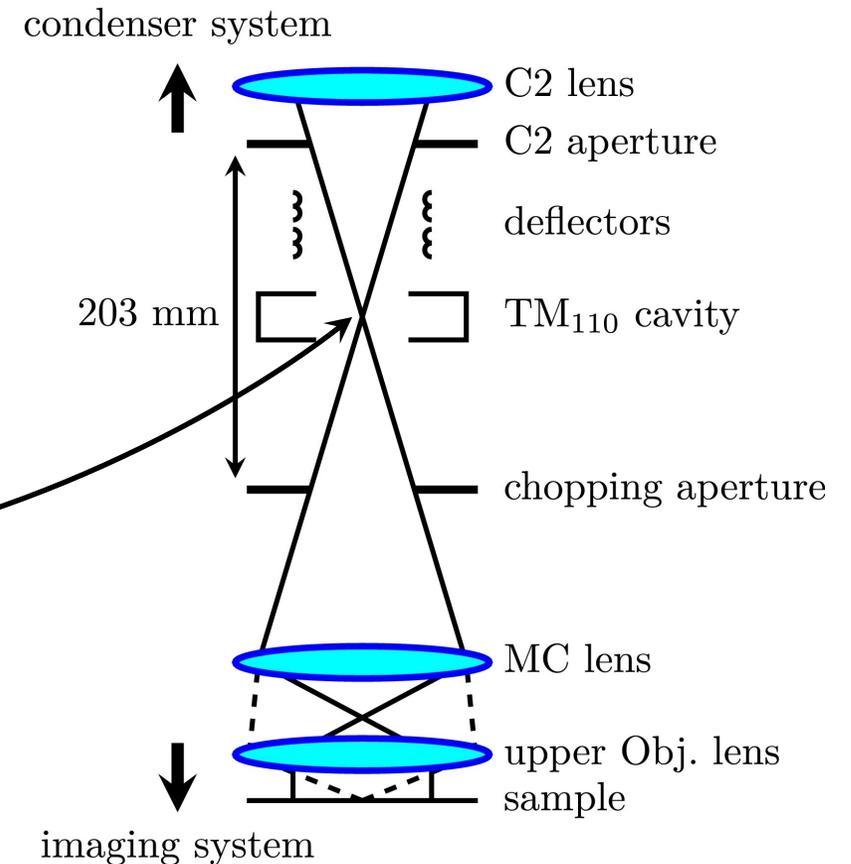
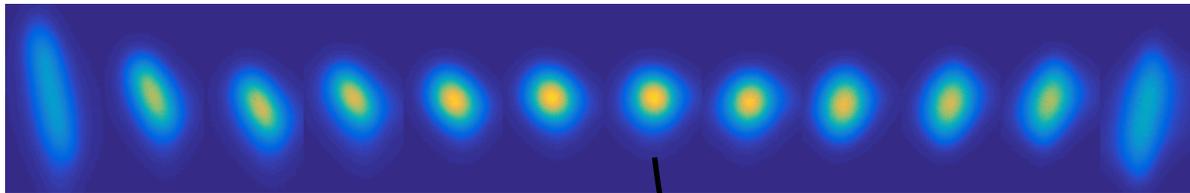


16.4 mm

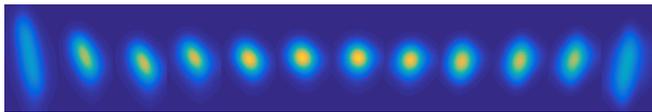
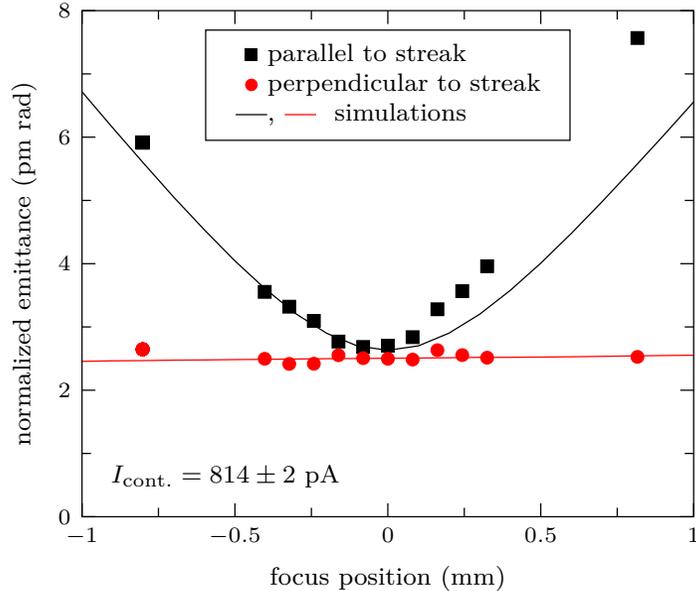


Conjugate Blanking Mode

Pulsed beam on camera at different positions of the crossover in the cavity

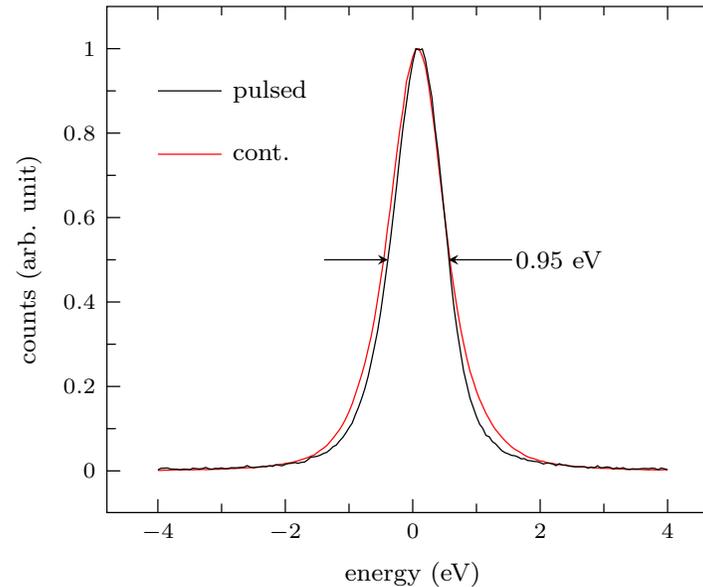


Conjugate Blanking Mode



Pulsed beam on camera at different positions of the crossover in the cavity

$$\varepsilon_{n,y} = \varepsilon_{n,x} = (2.5 \pm 0.2) \text{ pm rad}$$



Peak brightness and beam quality of the FEG are conserved

	Schottky FEG	Cavity-based source
ΔE_{FWHM} (eV)	(0.9 ± 0.05)	(0.95 ± 0.05)
B_{rms} (A / m ² sr V)	$(7.5 \pm 1) \times 10^6$	$(7 \pm 1) \times 10^6$

Dual mode TM₁₁₀ Cavity for Ultrafast Electron Microscopy

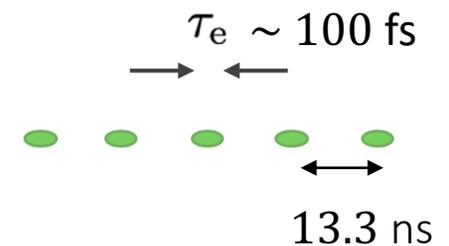
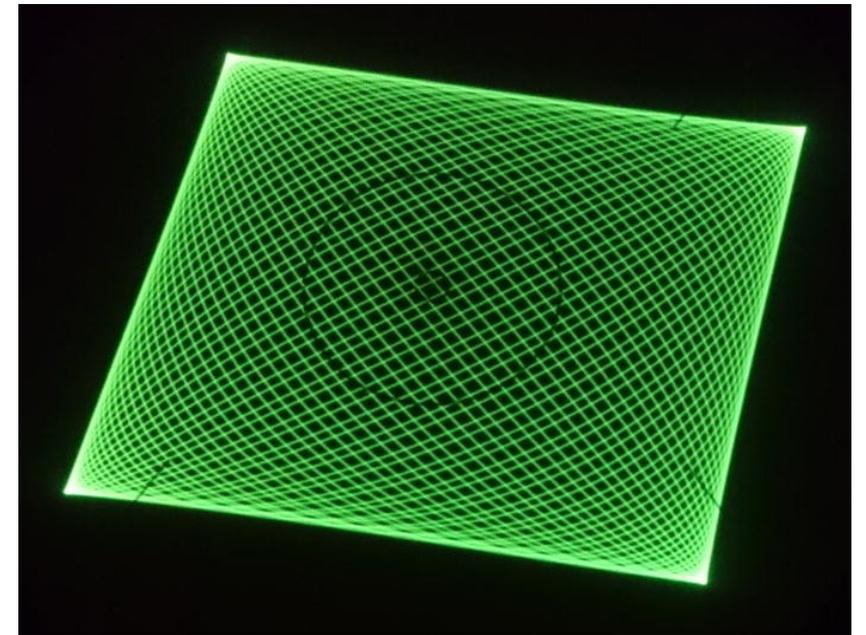


Two orthogonal modes @

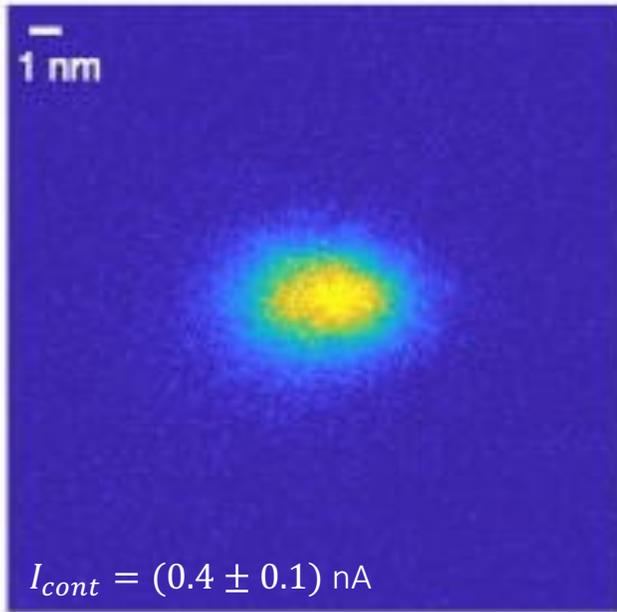
$$\nu_1 = 3.000 \text{ GHz}$$

$$\nu_2 = 3.075 \text{ GHz}$$

Lissajous pattern traced @ 75 MHz



Dual mode TM₁₁₀ Cavity in Conjugate Blanking Mode

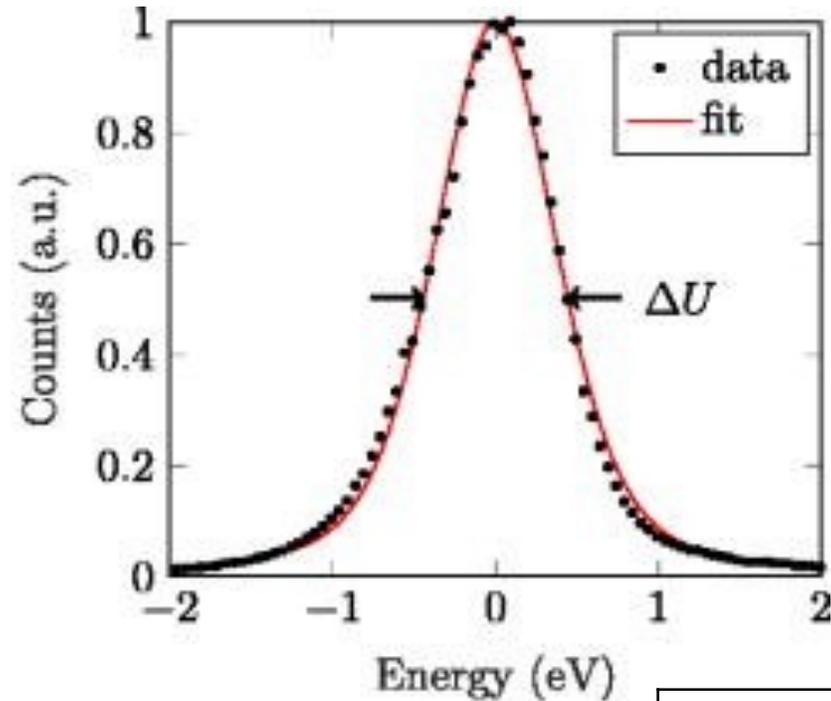


$$\varepsilon_{n,x} \text{ (pm rad)} = (2.1 \pm 0.2)$$

$$\varepsilon_{n,y} \text{ (pm rad)} = (1.3 \pm 0.2)$$

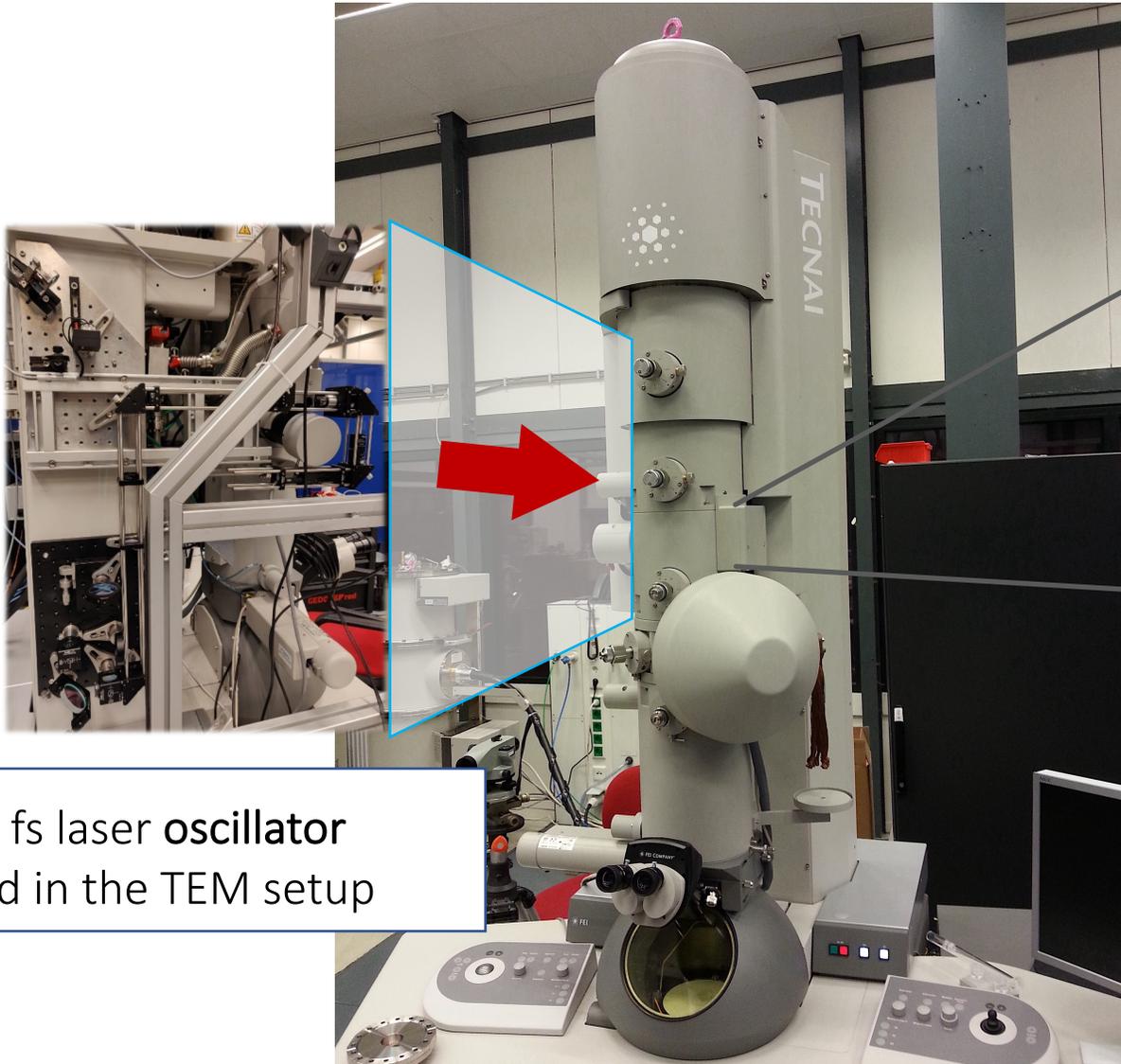
$$\tau = (630 \pm 10) \text{ fs}$$

@ Input Power $(3.7 \pm 0.1) \text{ W}$



	Schottky FEG	Cavity-based source
ΔE_{FWHM} (eV)	(0.9 ± 0.05)	(0.95 ± 0.05)
B_{rms} (A/m ² sr V)	$(7 \pm 1) \times 10^6$	$(7 \pm 1) \times 10^6$

RF-Cavity-Based UTEM



Dual mode TM_{110} cavity

75 MHz fs laser oscillator
integrated in the TEM setup

Electron pulses @ 75 MHz rep rate
synchronized to fs oscillator
within < 100 fs

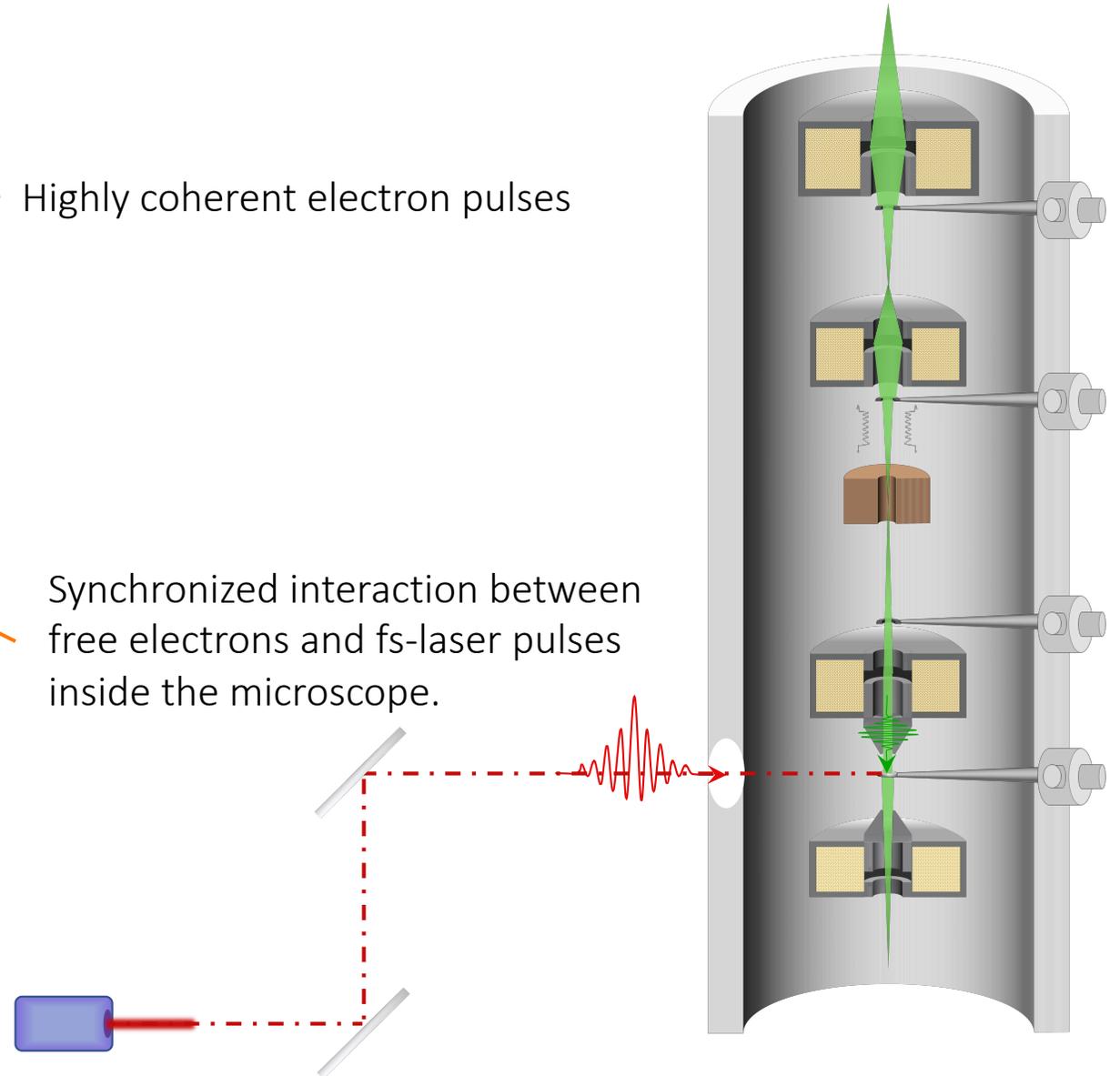
Coherent Manipulation of Electron Wavefunction with Light

Coherent manipulation and control of the electron's wavefunction with light

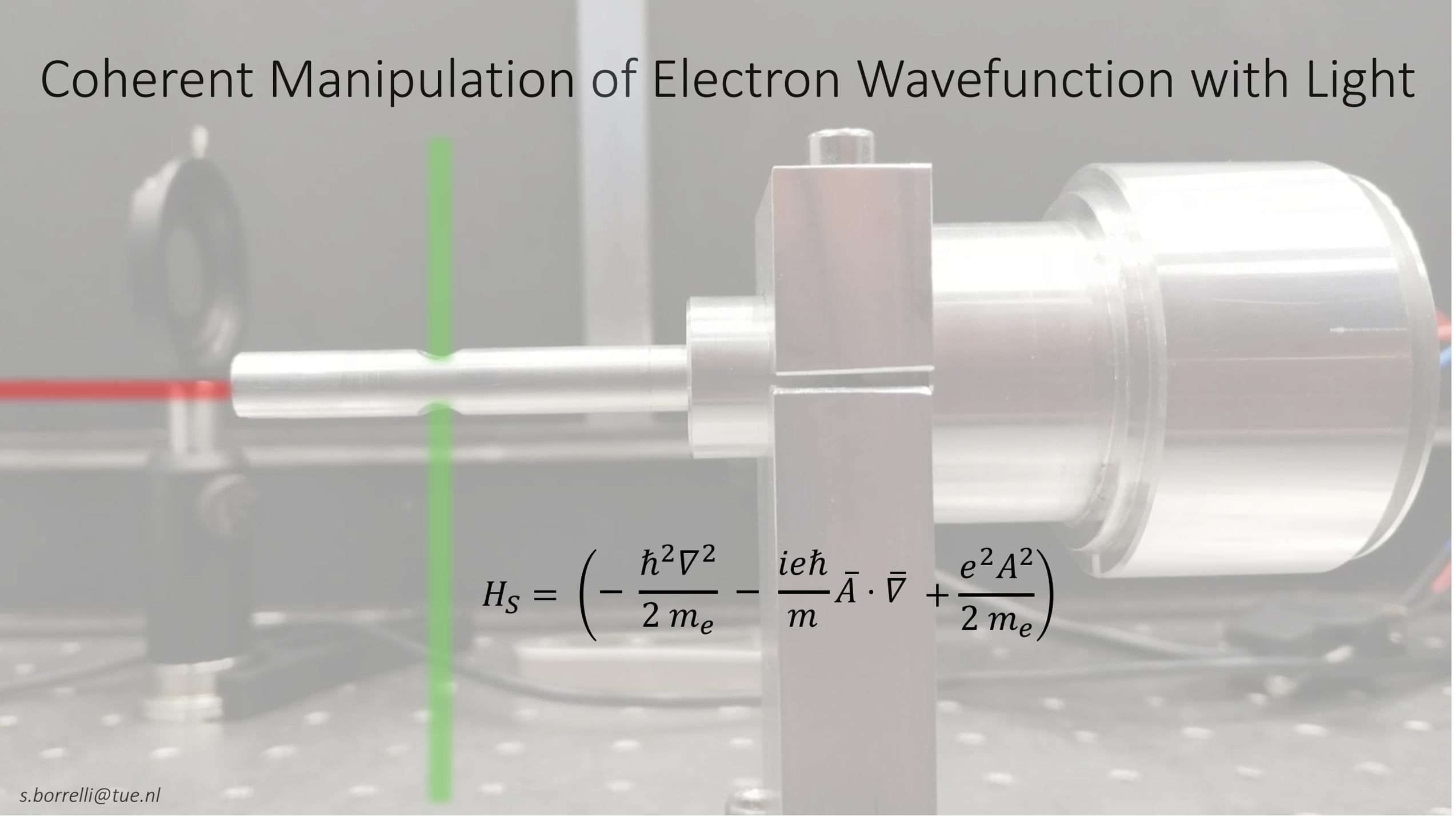
Highly coherent electron pulses

Synchronized interaction between free electrons and fs-laser pulses inside the microscope.

Establishing new free electron quantum optics based on the interaction of sub-ps electron pulses with the time-dependent electromagnetic fields of light.

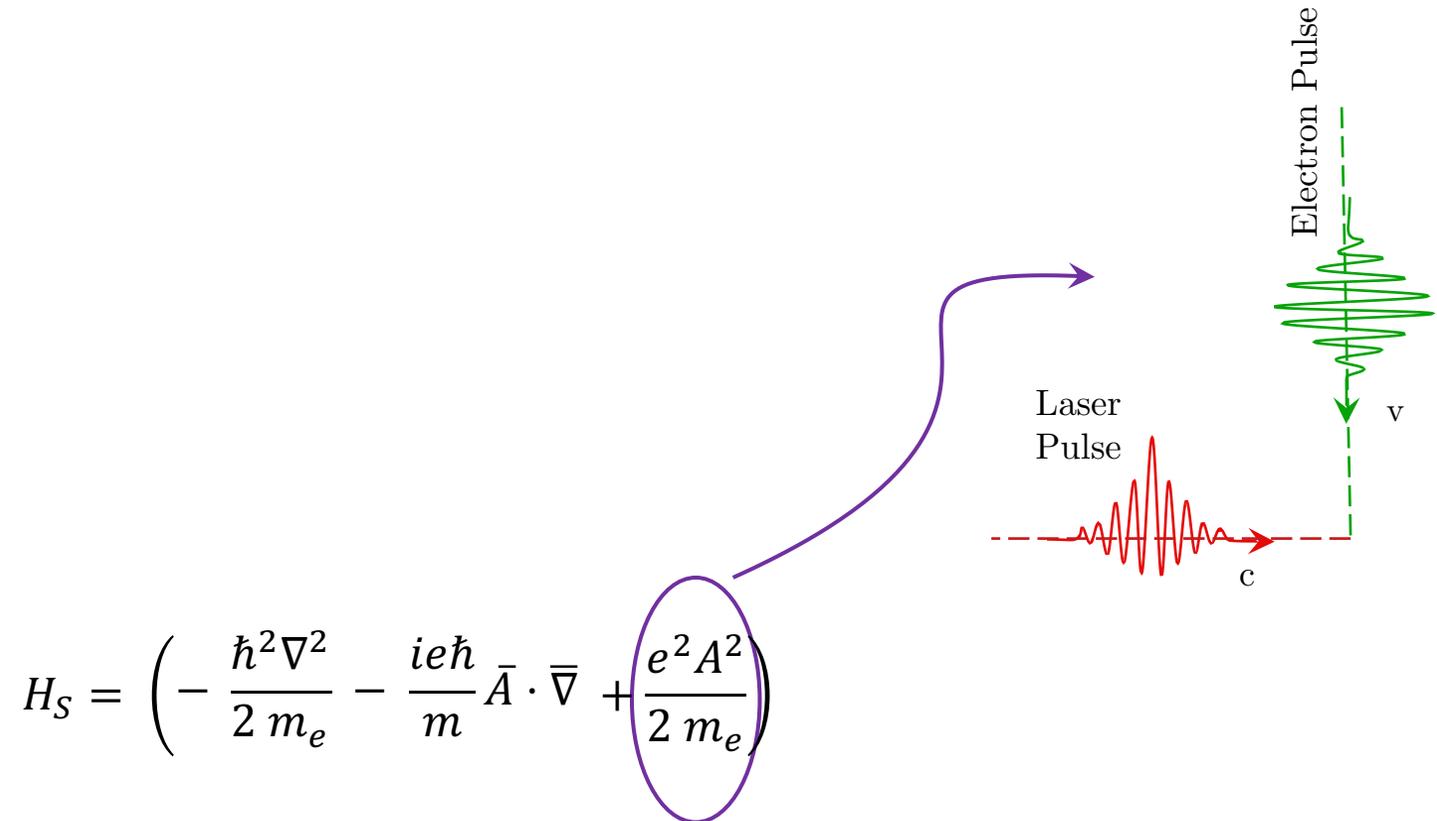


Coherent Manipulation of Electron Wavefunction with Light


$$H_S = \left(-\frac{\hbar^2 \nabla^2}{2 m_e} - \frac{ie\hbar}{m} \bar{A} \cdot \bar{\nabla} + \frac{e^2 A^2}{2 m_e} \right)$$

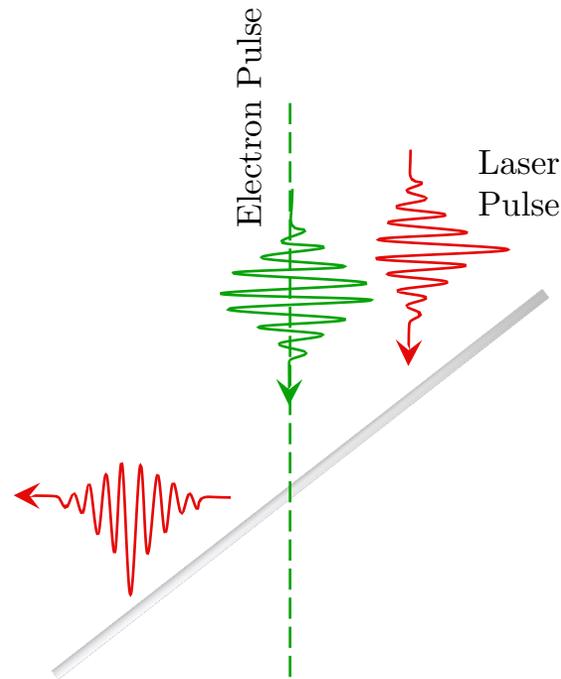
Coherent Manipulation of Electron Wavefunction with Light

Ponderomotive Phase Shaping



Coherent Manipulation of Electron Wavefunction with Light

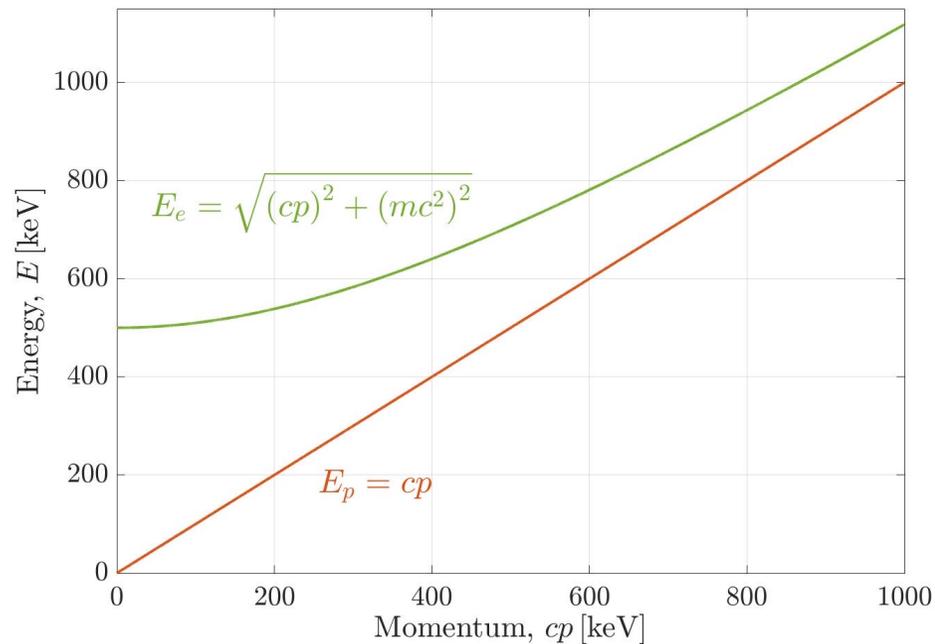
Photon-Induced Near-Field Electron Microscopy



$$H_S = \left(-\frac{\hbar^2 \nabla^2}{2 m_e} - \frac{i e \hbar}{m} \bar{A} \cdot \bar{\nabla} + \frac{e^2 A^2}{2 m_e} \right)$$

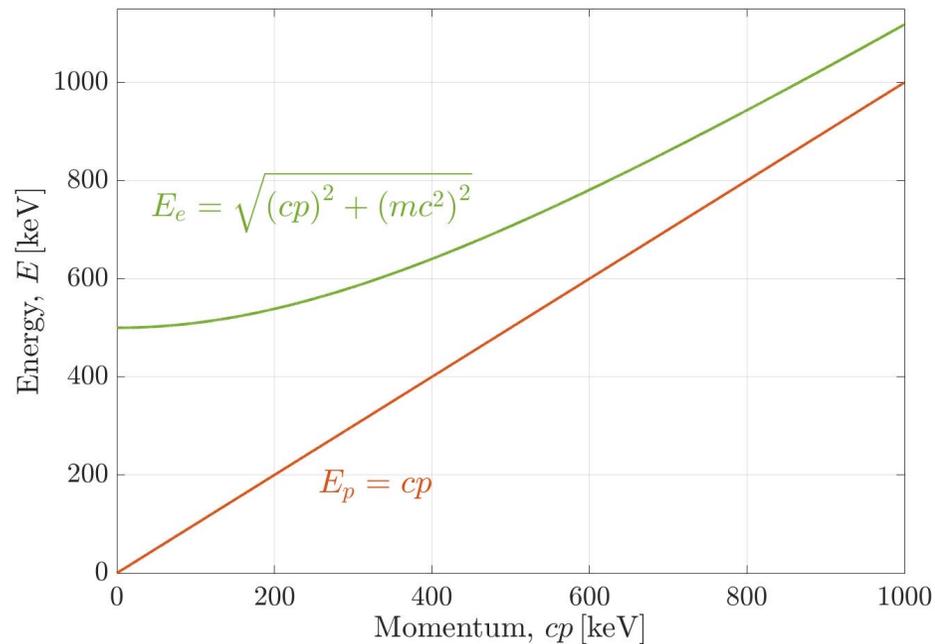
Photon-Induced Near-Field Electron Microscopy

$$H_S = \left(-\frac{\hbar^2 \nabla^2}{2m_e} - \frac{ie\hbar}{m} \vec{A} \cdot \vec{\nabla} + \frac{e^2 A^2}{2m_e} \right)$$



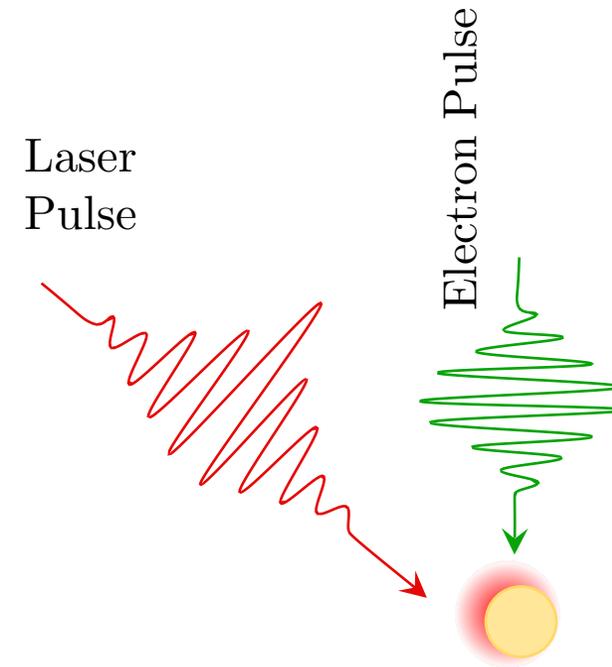
A free electron cannot
absorb/emit a photon

Photon-Induced Near-Field Electron Microscopy



A free electron cannot absorb/emit a photon

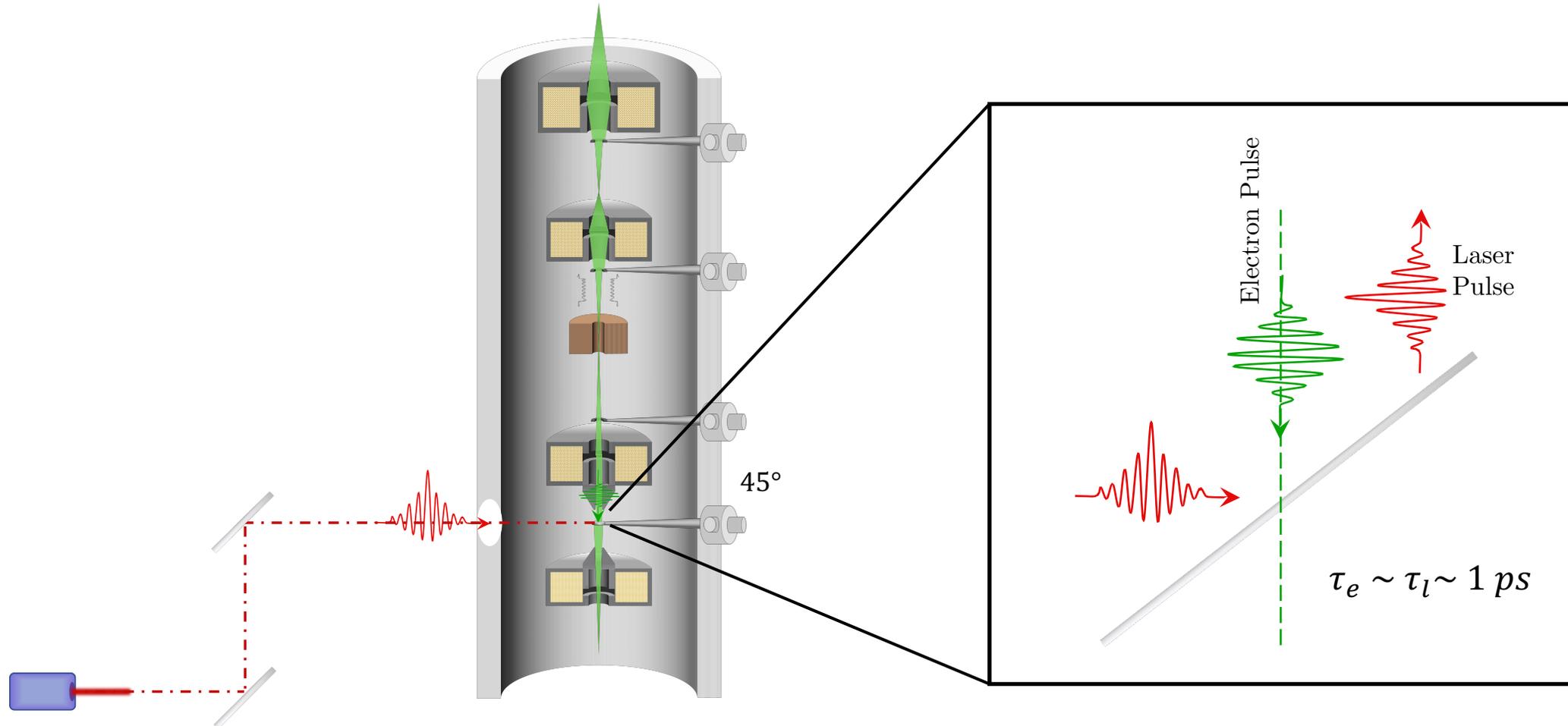
Dispersion relation is changed by the presence of matter



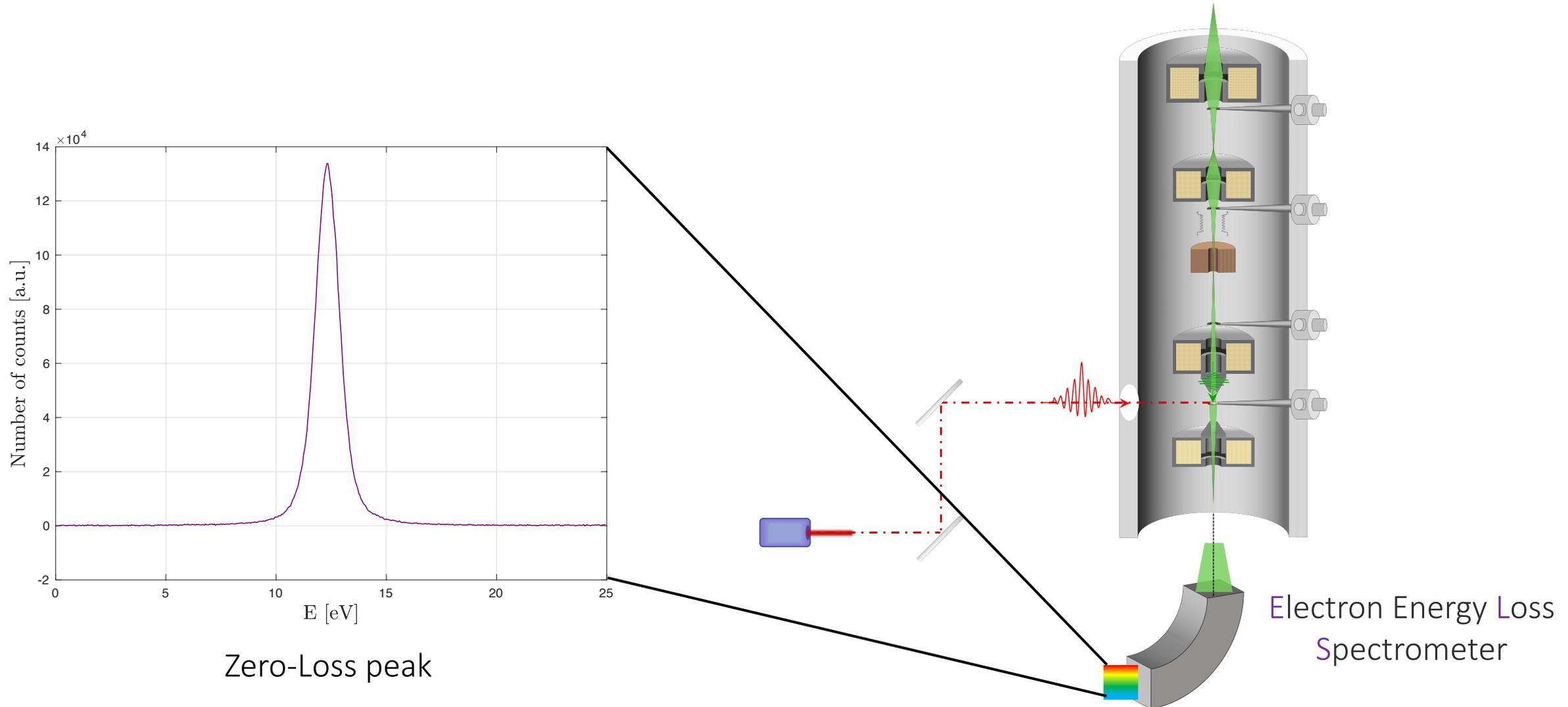
An electron can absorb/emit photons in the near-field of the object

Photon-Induced Near-Field Electron Microscopy

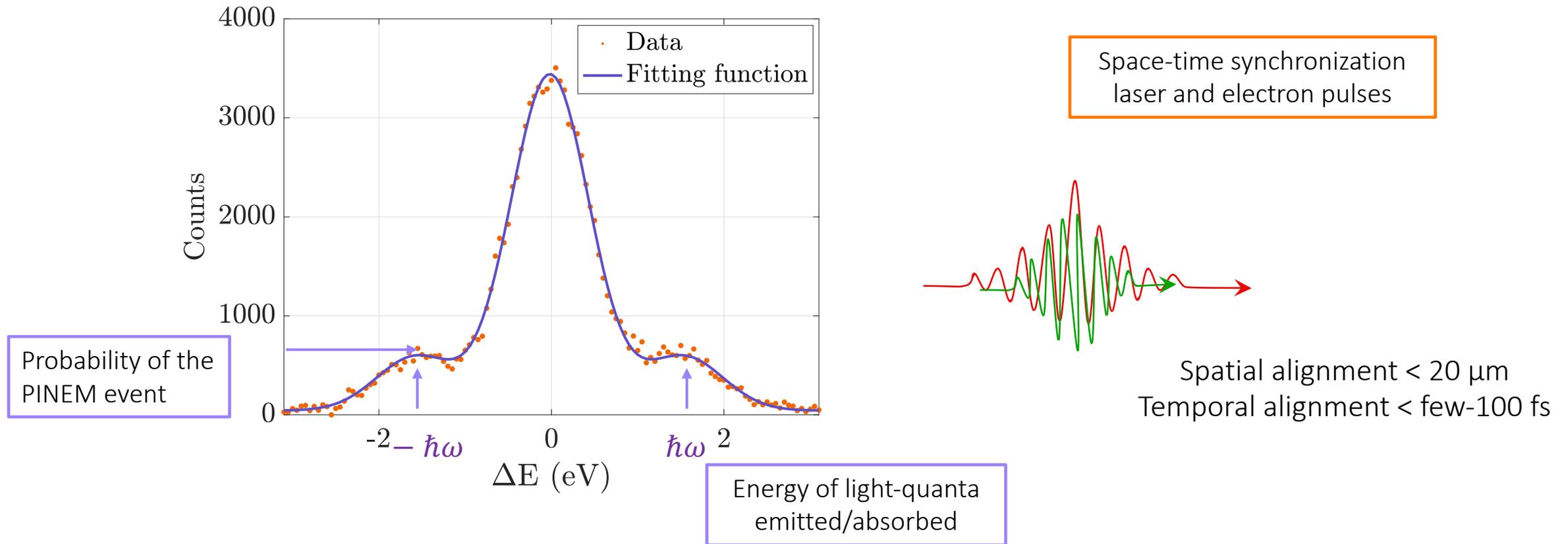
A test-bed of coherent manipulation of electrons with light & Diagnostic Tool



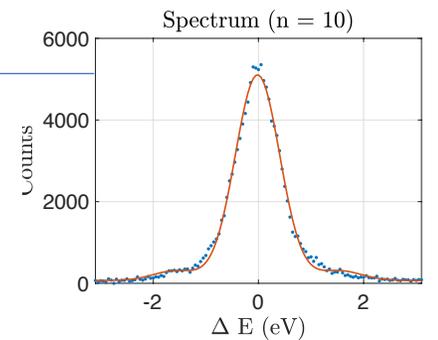
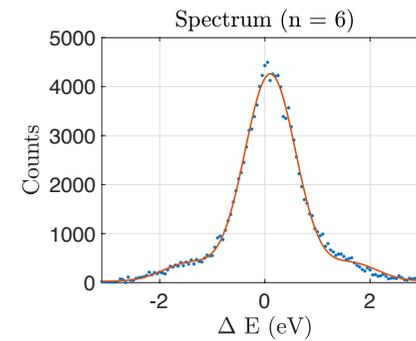
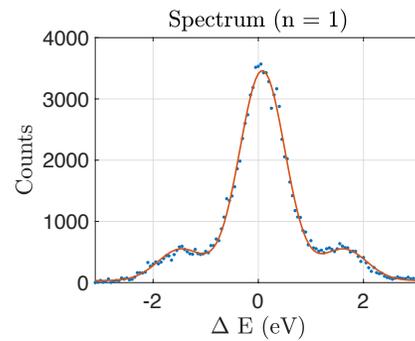
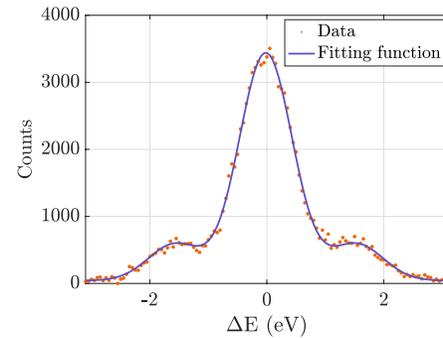
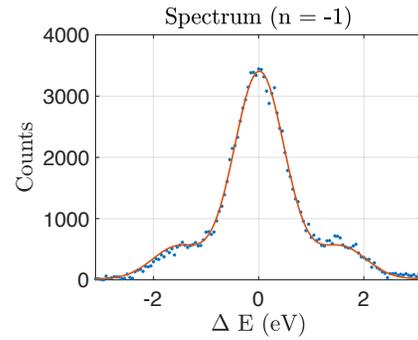
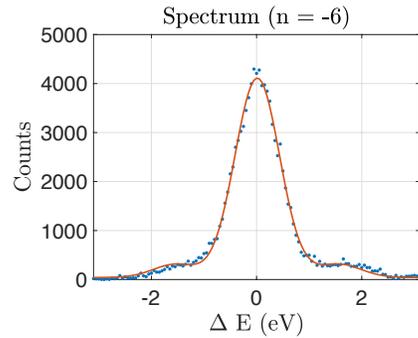
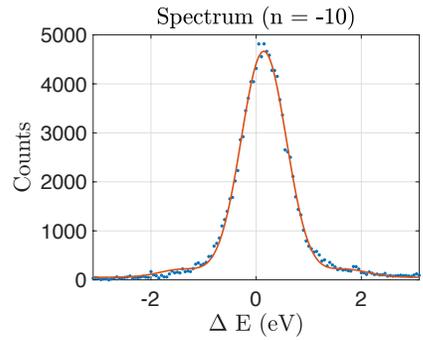
Photon-Induced Near-Field Electron Microscopy



Photon-Induced Near-Field Electron Microscopy



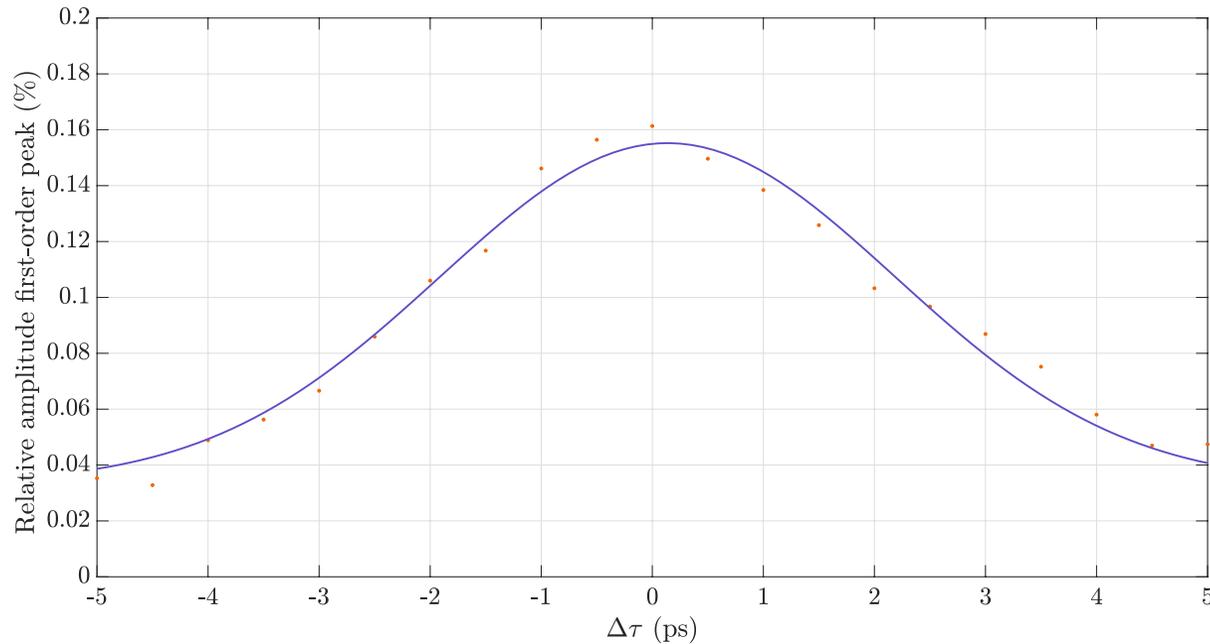
Photon-Induced Near-Field Electron Microscopy



Time Delay between electron and laser pulses

Photon-Induced Near-Field Electron Microscopy

Cross-correlation between laser and electron pulse length

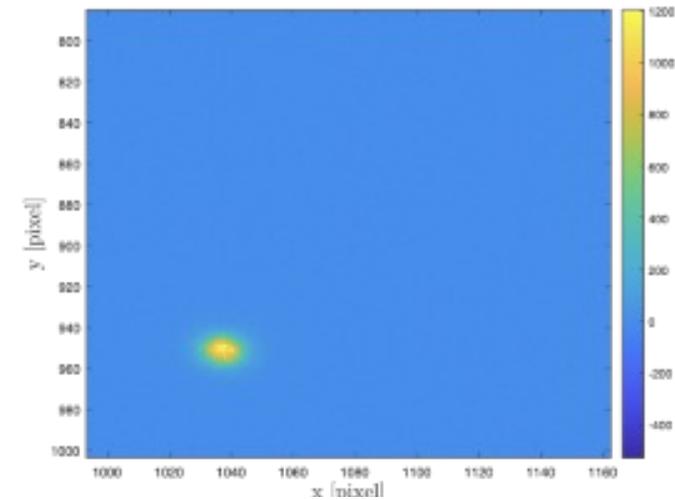


$$\tau = \sqrt{\tau_e^2 + \tau_l^2}$$

$\tau = 2.1 \text{ ps}$
 $\tau_l \sim 2 \text{ ps}$

$\Rightarrow \tau_e \sim 650 \text{ fs}$

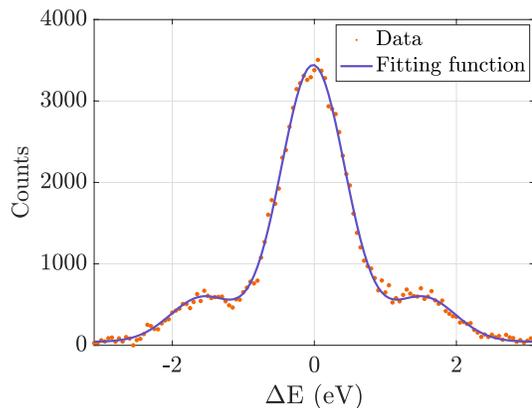
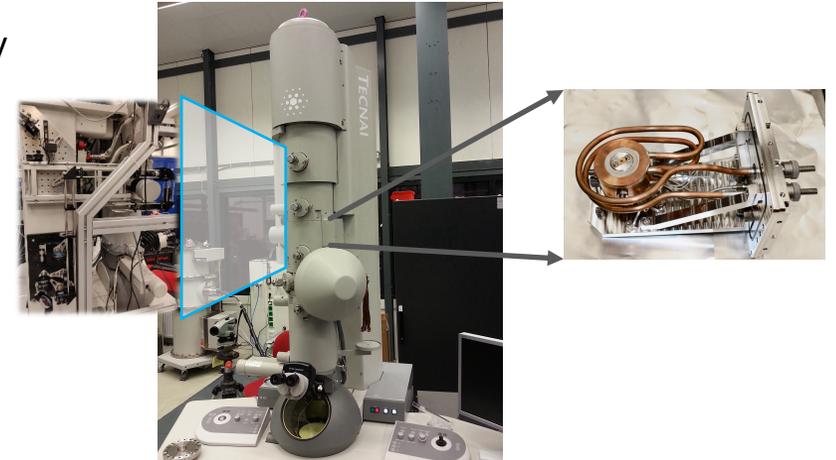
Preliminary



$$\tau_e = \frac{I_{\text{pulse}}}{I_{\text{cont}} * \text{Rep Rate}} \sim (630 \pm 10) \text{ fs}$$

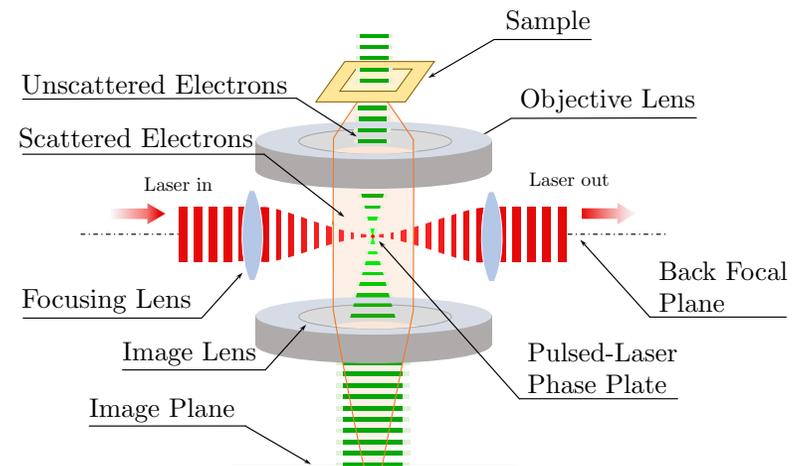
Wrap-up

- Pulse generation by beam chopping with miniaturized TM_{110} RF-cavity
- 100 fs pulses @ rep rate 3 GHz or 75 MHz
- Fast switching between continuous and pulsed mode operation
- High Brightness ($\sim 10^7$ A/m² sr V) and energy spread (0.9 eV)
- fs-laser oscillator integrated into the microscope



- Photon-Induced Near-field Electron Microscopy for electron pulse length measurements

- Shaping of the electron wavefunction with fs laser pulses for Zernike phase contrast microscopy





CQT Coherence and
Quantum
Technology

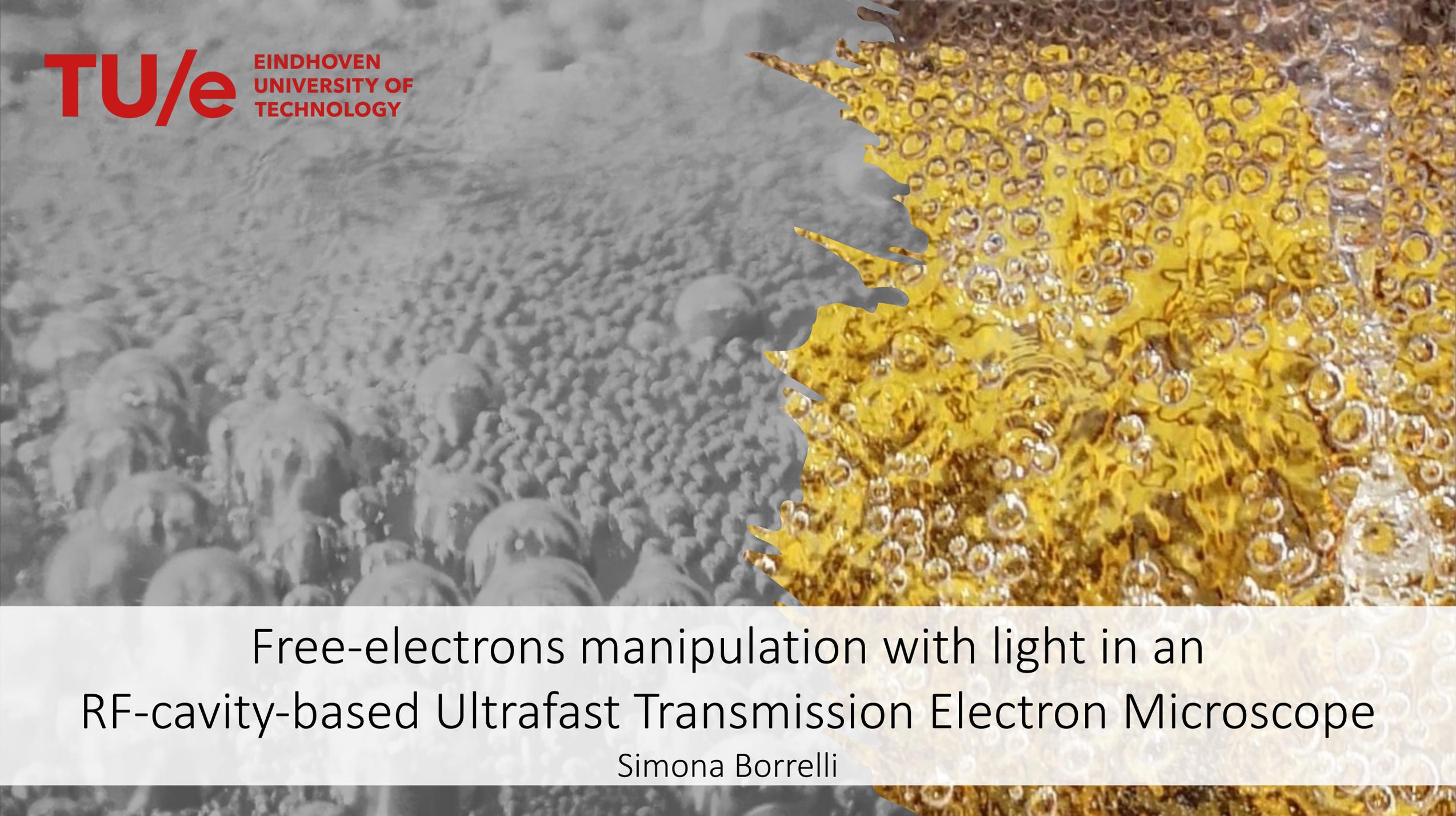


Thank you!



TU/e EINDHOVEN
UNIVERSITY OF
TECHNOLOGY



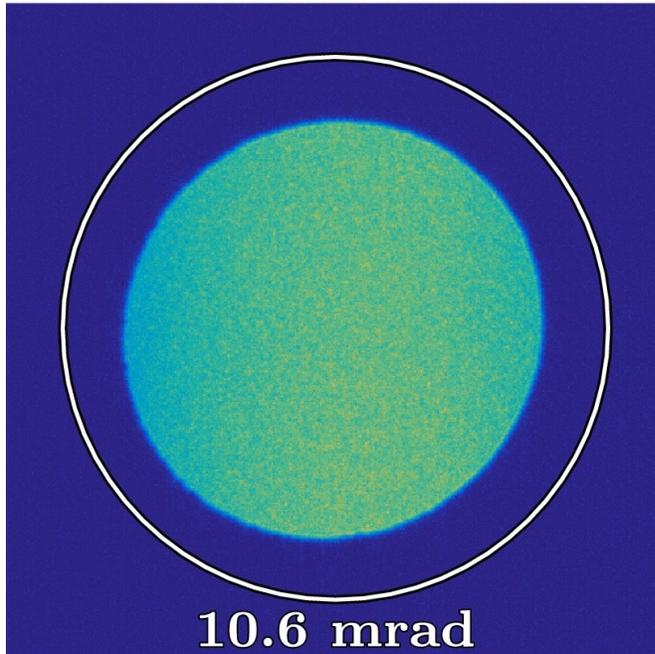
The background of the slide is a composite image. The left side shows a grayscale, textured surface, possibly a material's surface or a microscopic view. The right side shows a vibrant, golden-yellow liquid with many small, circular bubbles, resembling oil or a similar fluid. A jagged, torn-paper-like border separates the two images.

Free-electrons manipulation with light in an RF-cavity-based Ultrafast Transmission Electron Microscope

Simona Borrelli

Backup slides

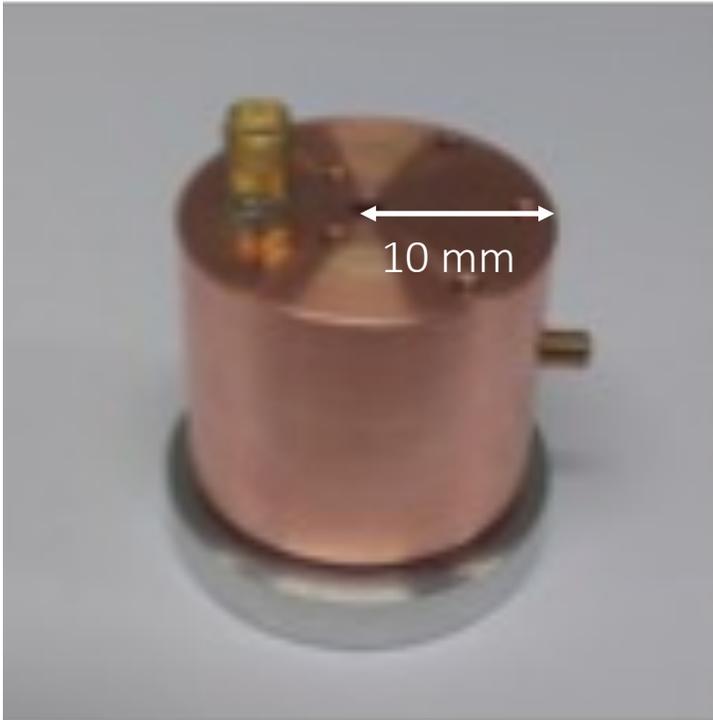
Angular Distribution of the Pulsed beam – Single Mode



Angles calibrated using a known diffraction ring at 10.6 mrad from a typical cross grating sample.

The focusing angle is determined to be 8.74 mrad.

Cavity Radius



16.4 mm

$$a = \frac{X_{11}}{\sqrt{\epsilon\mu} \omega_0}$$

3 GHz in vacuum

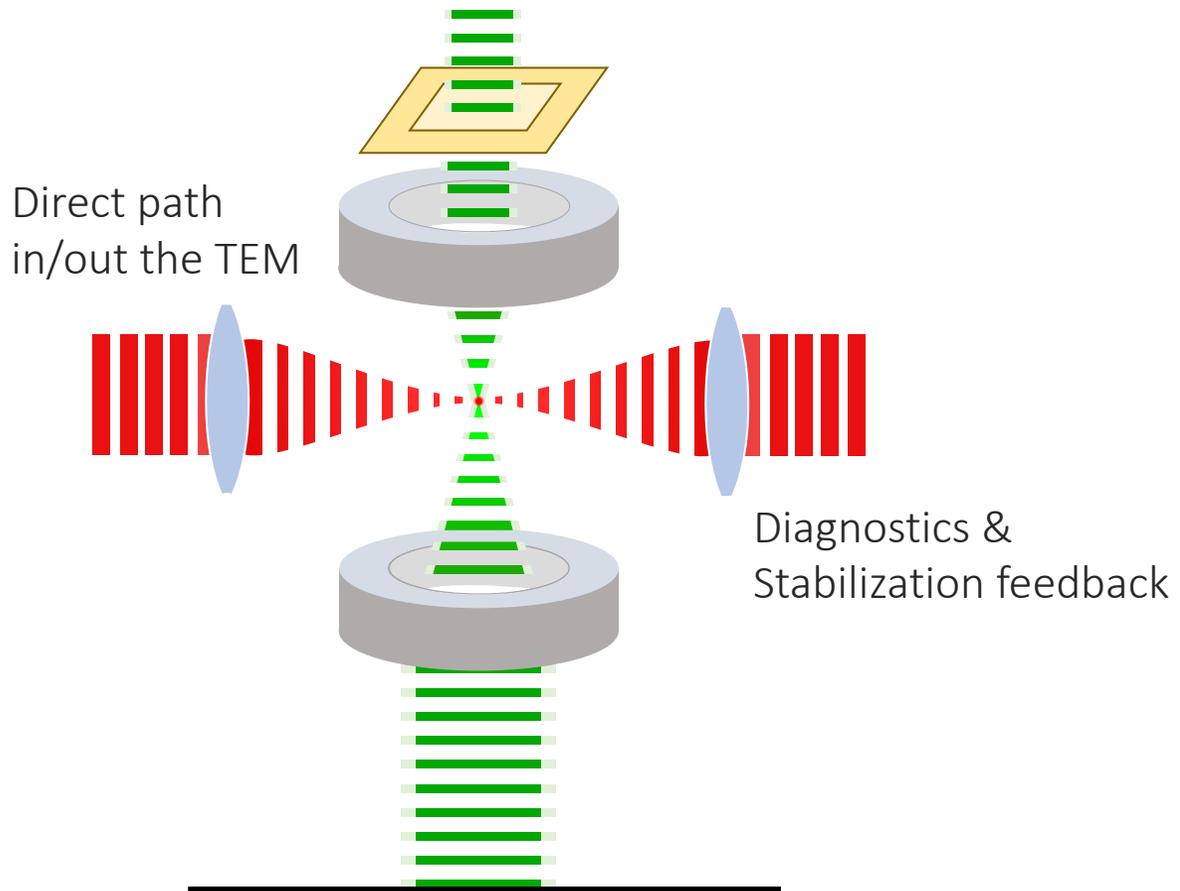
a = 60.9 mm

3 GHz with ZrTO4

a = 10 mm

Pulsed-Laser-Based Zernike Phase Plate

Spatial Alignment and Diagnostics



Temporal Alignment

